

**PATENT**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re the application of	)	
	)	
Bedell et al.	)	Group Art Unit: 2652
	)	
Application No. 10/602,462	)	Examiner: CHEN, Tianjie
	)	
Filed: 06/23/2003	)	Attorney Docket No.
	)	HIT1P006/HSJ920030045US1
For: MAGNETIC HEAD COIL SYSTEM)	)	
AND DAMASCENE/REACTIVE )	)	
ION ETCHING METHOD FOR )	)	Date: May 18, 2007
MANUFACTURING THE SAME )	)	
.....	)	

**AMENDMENT WITH RCE**  
**37 C.F.R. §1.114**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Examiner:

Together with the enclosed Request for Continued Examination (RCE, 37 C.F.R. §1.114) and prior to a first action on the merits, kindly amend the claims as indicated below. Applicant also submits the necessary fees.